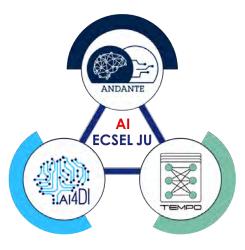
## The International Workshop on Edge Artificial Intelligence for Industrial Applications (EAI4IA)

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ECSEL JU

TEMPO

Vienna, Austria 25-26 July 2022 The International Workshop on Edge Artificial Intelligence for Industrial Applications (EAI4IA)



S2ORC-SemiCause: Annotating and Analysing Causality in the Semiconductor Domain

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## **Introduction: FMEA**



Infineon		RPNbase: FE-Process-FM	84 EA	If you change O and D,please make sure you have defined corresponding recommended actions for reduction of both O and D and documented it			or	Potential Failure Mode and Effects Analysis restricted Template version 5.0										
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FMEA (Failure Mode and Effect Analysis):

- Semi-structured data for cause-effect relation
- Fundamental Tool for Quality Management.



Decreasing the Ar flow rate causes a decrease of the etch rate.

**Motivation:** extract cause-effect relation from free text to:

- Convert free text to structured data
- Easier access to large number of cause-effect relations
- Eventually provide input for FMEA analysis

## Introduction: Machine learning method



• **Goal**: Extract cause-effect pairs from free texts

Decreasing the Ar flow rate causes a decrease of the etch rate.

- <u>Task:</u> information extraction (IE)
  - Extract and classify span
  - Extract relation
- <u>Method:</u> supervised learning
  - Requires annotated data

#### Introduction: Annotated cause-effect data

#### BECauSE

We are in serious economic trouble because of inadequate regulation

#### BioCause

In the case of PmrB, a normal response to mild acid pH requires not only a periplasmic histidine but also several glutamic acid residues. *Therefore*, regulation of PmrB activity may involve protonation of one or more of these amino acids.

#### S2ORC-SemiCause

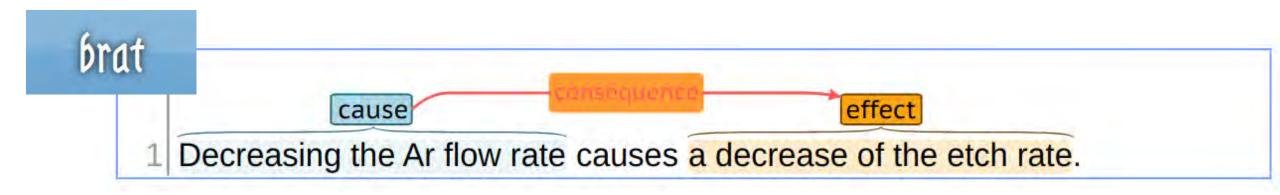
Decreasing the Ar flow rate causes a decrease of the etch rate.

• Existing annotated data in different domain:

- News: BECauSE
- Bio-medical: BioCause
- No existing data in semiconductor domain --> S2ORC-SemiCause



### Annotation: Inter-annotator-agreement (IAA)



	Iteration 1	Iteration 2
Relation Cohen's ĸ	0.65	0.80
Cause F1	0.55	0.71
Effect F1	0.60	0.81
BEcauSE span F1		Reference for machine learning performance

 Improved IAA for iter 2, due to updated guideline

KNOW

Center

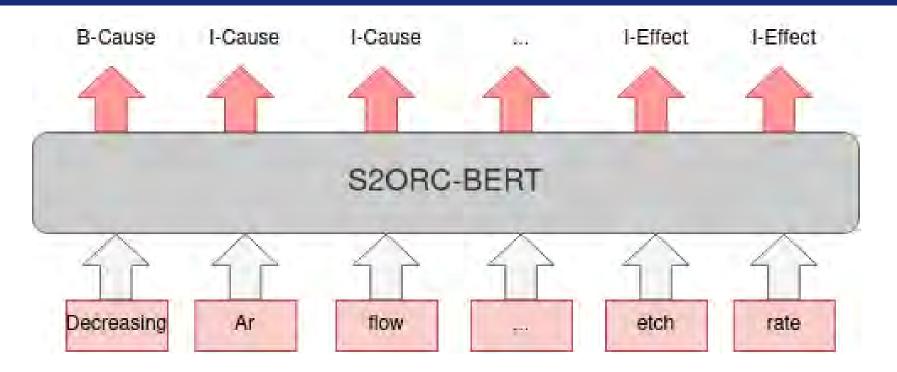
Infineon

• IAA as measured by span F1 comparable to BEcauSE

2 Annotators on same data; 2 iterations

#### **Baseline Model**





Decreasing the Ar flow rate causes a decrease of the etch rate.

Baseline model:

transfer learning from pretrained-S2ORC-BERT for token-classification task



Annotation

	F1	F1 partial overlap				
Cause	0.48 ± 0.02	$0.59 \pm 0.01$				
Effect	0.50 ± 0.03	$0.62 \pm 0.02$				

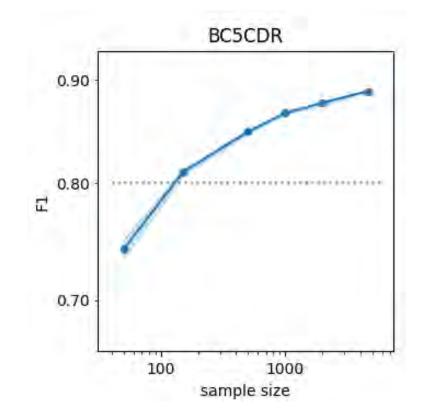
These safe zones are provided to a model predictive controller as reference

to generate feasible trajectories for a vehicle

- Baseline performance stable against random initialization
- Model performance lower than other datasets (token classification)

#### Compare to other datasets





	Avg span length
S2ORC-SemiCause	9.4 ± 7.2
BC5CDR	$1.4 \pm 1.3$

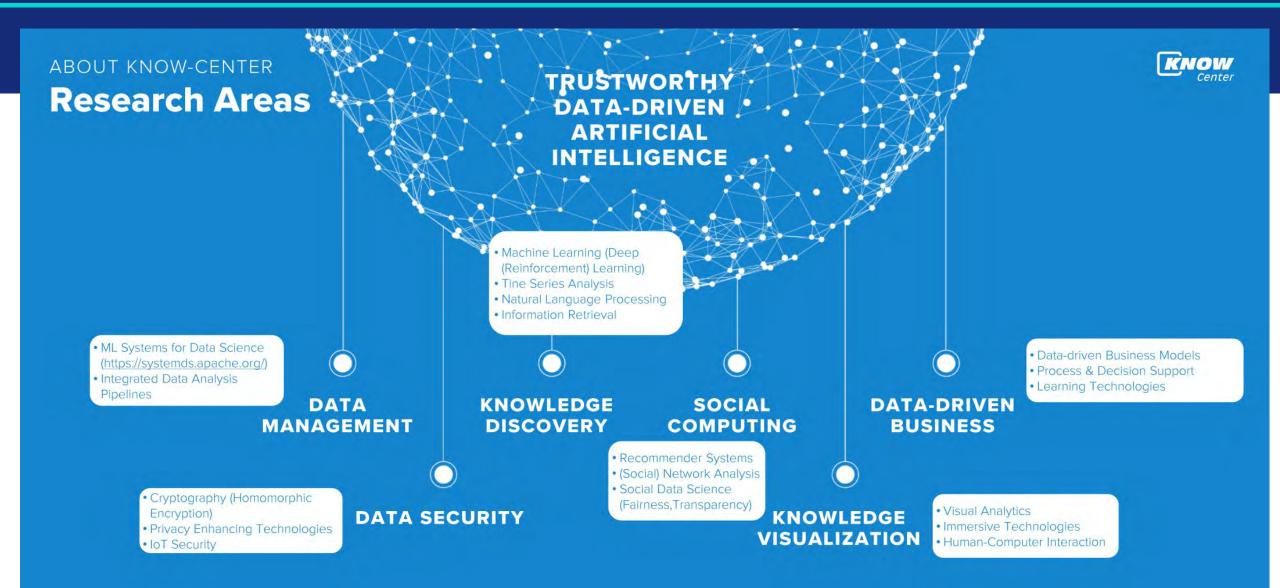
- Finetuning BERT typically reach ~90%
   F1 for token classification
  - Lower performance for smaller training data size (e.g. S2ORC-SemiCause)

 S2ORC-SemiCause dataset has much longer span length

#### Conclusion



- S2ORC-SemiCause dataset: annotated cause-effect relations for free text in semiconductor domain (scientific publications)
- Baseline model available for extracting causes and effects
- Long span length challenging for state-of-the-art token classification models



### **Event Organisers**







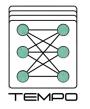


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# Thank You For your attention

